FORM PTO-1449 (Rev. 2-32) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE

Sheet 1 of 2

CHEMICAL-ORGANIC PLANARIZATION PROCESS FOR ATOMICALLY SMOOTH INTERFACES

ATTY. DOCKET NO.	SERIAL NO.
0937.0017	09 902 408

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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APPLICANT: Gerald T. Mearini and Laszlo Takacs

FILING DATE	GROUP
July 10, 2001	2817

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB-CLASS	FILING DATE IF APPROPRIATE
RRB		5 7 4 8 3 5 0	5/5/98	Pan et al	359	130	6/19/96
		6 2 0 5 2 7 0	3/20/01	Cao	385	24	9/23/99
		6 2 3 3 2 6 1	5/15/01	Mesh et al	372	32	6/9/99
		5 5 2 9 6 7 1	6/25/96	Debley et al.	204	192.34	7/27/94
		5 7 2 5 4 1 3	3/10/98	Malshe et al	451	41	5/6/94
		4 7 4 7 9 2 2	5/31/88	Sharp	204	192.11	3/25/86

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION YES	TRANSLATION NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

			Kumar, et al.; *Near-Infrared Bandpass Filter from Si/SiO$_2$*; Multilayer Coatings; February 1999
			Suntola, T.; *Cost-Effective Processing by Atomic Layer Epitaxy*;.1993
			Bachman, et al.; *Molecular Layer Expitaxy by Real-Time Optical Process Monitoring*; Department of Materials Science and Engineering, North Carolina State University, 1997.
			H., Kawai, T. Tabata; *Atomic Layer Control of the Growth of Oxide Superconductors Using Laser Molecular Beam Epitaxy*; 1997.
			Spiller, E;*Smoothing of Multilayer X-Ray Mirrors by Ion Polishing*; IBM Research Division, Thomas J. Watson; 1993.
			Puik, E.J, van der Wiel and Zeijlemaker, H, and Verhoeven, J.; *Ion Etching of Thin W Layers: Enhancing Reflectivity of W-C Multilayer Coatings*; March 30, 1989.
			Nishizawa, J., Abe, H., and Kurabayshi, T.*J. 132(5) (1985).*
			Puik, E.J., et al.; *Appln. Surf. Sci. 47 (1991) 251.*
RRB			Kloidt, A, et al.; *Thin Sol Films, 228 (1993) 154.*

EXAMINER: R Burch

DATE CONSIDERED: 6-24-04

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RRB	Imai, F., Kunimori, K., and Nozoye, H; *Novel Epitaxial Growth Mechanism of Magnesium Oxide/Titanium Oxide Ceramics Superlattice Thin Films Observed by Reflection High-Energy Electron Diffraction;* November 8, 1993.
RRB	Kildemo, et al.; *Real Time Control of the Growth of Silicon Alloy Mulitlayers by Multiwavelength Ellipsometry*; 1996.

EXAMINER	DATE CONSIDERED
R. Bueker	6-24-04

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